



Nanostructured Photovoltaic Devices

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Message from the Guest Editor

Nanostructured photovoltaics have already proven rapid developments and are marked to revolutionize our everyday life. The exciting developments in the field of the light trapping features of nanostructures and solar cell nano-engineered architecture present challenges with unique opportunities to explore new ideas regarding nanostructure integration into photovoltaics.

In this Special Issue of *Micromachines* we invite contributions on the latest developments on nanostructured photovoltaics with improved efficiency from all types of solar cells employing nanostructures, low dimensionality features and emerging technologies in nano-integration. We would like to open the discussions for future directions and challenges in the development of nanostructured photovoltaic devices.





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Message from the Editor-in-Chief

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